



Session Title:	[WeD1] Lithography Process I
Session Date:	November 13 (Wed.), 2024
Session Time:	09:00-10:15
Session Room:	Room D (Sidney Room, 2F, Paradise Hotel Busan)
Session Chair:	Prof. Chawon Koh (Yonsei Univ., Korea)

[WeD1-1] [Invited] - Online

09:00-09:45

EUV Lithography – Latest Progress and Outlook

Anthony Yen (ASML, USA)

[WeD1-2] [Invited]

09:45-10:15

Advanced Lithography Technology Materials towards Next Generation; Challenges and Opportunities

Toru Kimura (JSR Corp., Japan)